

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination KIM ET AL.	
		Examiner Natasha Young	Art Unit 1797	Page 1 of 1

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*	C US-6,590,139 B1	07-2003	Lee et al.	800/24
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L	US-			
M	US-			

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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a))  
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